

DLR8240

300mm Wafer Sorter
SEMI S2-0715

APPROVED



Dual Robot Transfer System. Extremely High Transfer Speed !

Characters & Advantages

- The internal mini-environment cleanliness control is verified by the CFD analysis, which ensures the internal and external pressure-differential design to prevent from pollution in the wafer transfer process.
- The compact design can reduce footprint and saves costs.
- Optimized moving track of the robot, enabling a speedy and stable transfer with the curve interpolation for the shortest route.
- The ultra-high speed wafer aligner, which uses the dynamic image algorithm, can accurately and quickly allocate the wafer center and direction.
- With the optical and image processing & identification system, it enhances the identification rate of wafer ID.
- Complete data track to satisfy the requirement of predictive maintenance of Industry 4.0.
- Customized services, providing discussions for customized specifications.

Specification

Item	Specification
Number Of Ports	4 Ports
Transferring Object	300mm Wafer : dia.300±0.2mm, Thickness : 775µm
Robot *	SAD201-R03000705S-Z350
Aligner* @Vacuum	HA-300V
WPH @Aligner+OCR	520 WPH
Repeat Accuracy	±0.1mm
Cleanliness	Class 1 @ 0.1µm (PTFE)
Option	Wafer ID Reader, Robot Auto Teaching Function
Power Supply	220VAC 50Hz/60Hz 1PH 12KVA
Weight	931 kg

*Edge-Clamp wafer handling is also available.

Dimensions

